

Linton



KX240MCZR

Semiconductor Crystal Growing Furnace

- Capable of Growing Ingot Diameters 8" (200 mm), 10" (250 mm), 12" (300 mm)
- Advanced Control System
- Low Power Consumption
- Integrated Communications with optional WINGS system
- Complete Customization Available



KX240MCZR

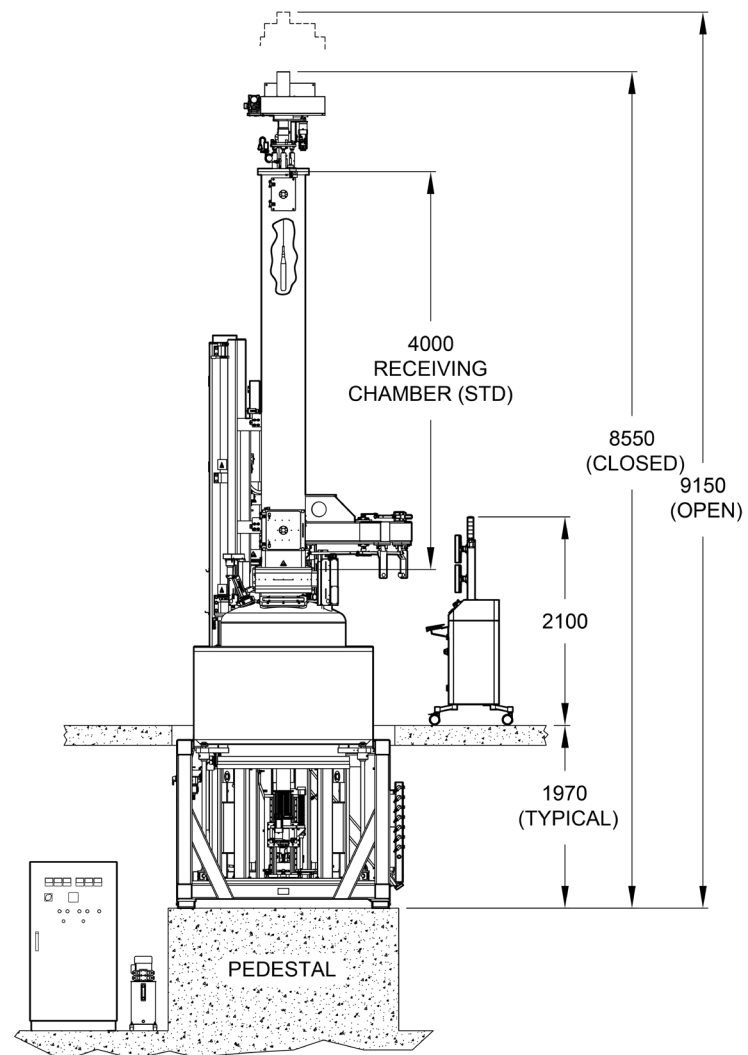
Semiconductor Crystal Growing Furnace

The KX240MCZR is designed to easily accommodate different sized hotzones and produce 8-12 inch crystals (200 to 300mm) to track with your changing needs and ensure you get a long life from your investment. Optional field-upgrades are available for receiving chamber heights (3000, 3500 and 4000 mm), and throat diameters (350 and 400 mm). The KX240MCZR is magnet-ready—options include a 1,000-gauss resistive cusp magnet.

PERFORMANCE	
Furnace Chamber Diameter	1100 mm (43.3 in) – Standard 1200 mm (47.2 in) – Optional
Receiving Chamber Height	4000 mm (157.5 in) – Standard 3500 mm (137.8 in) – Optional 3000 mm (118.1 in) – Optional
Throat Diameter	350 mm (13.8 in) – Standard 400 mm (15.7 in) – Optional
Seed Lift Rate	0-508 mm/hr
Seed Jog Speed (Nominal)	400 mm/min
Seed Rotation (Reversible)	0-30 rpm
Total Crucible Travel	550 mm (21.7 in)
Crucible Lift Rate	0-127 mm/hr
Crucible Jog Speed (Nominal)	127 mm/min
Crucible Rotation (Reversible)	0-20 rpm

SILICON CHARGE CAPACITY		
*Hot Zones available to fit following crucible size. Note: Charges enhanced with Xtramelt™ Feeder		
CRUCIBLE DIAMETER*	CRUCIBLE HEIGHT*	NOMINAL CHARGE SIZE
24.0 in	343 mm (13.5 in)	220 kg
26.0 in	483 mm (19.0 in)	300 kg
28.0 in	496 mm (19.5 in)	350 kg

OPTIONS & ACCESSORIES	
Feeders	Vacuum Pumps
Hot Zones	Ingots and Crucible Handling
Filters	Maintenance Tools



Dimensions shown are typical and can be customized to meet customer requirements